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U.S. ARMY ELECTRONICS RESEARCH AND DEVELOPMENT COMMAND
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THIRTY SECOND ANNUAL FREQUENCY CONTROL SYMPOSIUM

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179-1961 Piezoelectric Ceramics, Methods of Measurement of (ANSI C83.24-1962) (Reaff 1971) \$ 3.50	to Publication 314A (1971) First Supplement to Publication 314 (1970) \$12.60 Contents. Guide to the Use of
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RS-367, Dimensional and Electrical Characteristics Defining Receiver Type Sockets. (Including crystal sockets.) \$15.00	Publication 368 (1971) \$16.00 Contents. Piezoelectric Ceramic Filters
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Table of Contents

the second section of the second section of the second section of the second section s	
Fundamental Properties of Quartz	Page No.
The Characterization of Synthetic Quartz By Using Infra-Red Absorption - J. C. Brice and A. M. Cole, Philips Research Laboratories	in place
Low Temperature Infrared Absorption of Impurities in High Grade Quartz - H. G. Lipson, F. Euler and A. F. Armington, Rome Air Development Center	11
Steady State Radiation Effects in Precision Quartz Resonators - F. Euler, P. Ligor, A. Kahan and P. Pellegrini, Rome Air Development Center, T. M. Flanagan, JAYCOR and T. F. Wrobel, IRT	24
Radiation Induced Frequency and Resistance Changes in Electrolyzed High Purity Quartz Resonators - T. J. Young, D. R. Koehler, R. A. Adams, Sandia Laboratories	34
Electrical and Acoustic Emission During Ferrobielastic Twinning in Quartz - T. W. Cline, J. W. Laughner, R. E. Newnham and L.E. Cross, The Pennsylvania State University	43
Surface Acoustic Wave Devices, Properties and Applications	
SAW Devices for Use in a High Performance Television Tuner - R. E. Stigall, Texas Instruments Inc. and W. R. Shreve, Hewlett Packard	50
Design and Construction of SAW Oscillators for Secondary Radar Systems - H. Eschler, L. Sanchez-Hermosilla, W.E. Bulst and P. Schucht, Siemens AG	58
Vibration Effects on Close in Phase Noise of a 300 MHz Surface Wave Resonator Oscillator - R. Allison and S. J. Goldman, Texas Instruments Inc	66
Improved Long-Term Aging in Deeply Etched SAW Resonators - C. A. Adams and J. A. Kuster, Hewlett-Packard Co	74
Higher Order Temperature Coefficients of Quartz SAW Oscillators - D. Hauden, M. Michel, J. J. Gagnepain, CNRS	77
A New Cut of Quartz Giving Improved Temperature Stability to SAW Oscillators - I. Browning and M. Lewis, R.S.R.E	87
Temperature Stable Shallow Bulk Acoustic Wave Devices - K. H. Yen, K. F. Lau and R.S. Kagiwada, TRW Defense and Space Systems Group	95
Temperature Compensation of Crystals with Parabolic Temperature Coefficients - R. G. Kinsman, Motorola , Inc	102
Resonator Theory	
Thickness-Shear, Thickness-Twist, and Flexural Vibrations of Rectangular At-Cut Quartz Plates with Patch Electrodes - P.C.Y. Lee, C. Zee and C.A. Brebbia, Princeton University	108
A New Method to Analyse Vibrations of Resonators by the Combination of Plate Equations	100
and Finite Element Method - Y. Mochizuki, Shizuoka University	120
Finite Element Analysis of At-Cut Crystals - D. C.L. Vangheluwe, Philips Eindhoven	134
Discrete Element Modeling of AT - Quartz Devices - L. N. Dworsky, Motorola, Inc	142
Temperature Derivatives of the Fundamental Elastic Constants of Quartz - B.K. Sinha and H.F. Tiersten, Rensselaer Polytechnic Institute	150

Temperature Induced Frequency Changes in Electroded Doubly-Rotated Quartz	Page No.	
Thickness-Mode Resonators - H. R. Fiersten and B. K. Sinha, Rensselaer Polytechnic Institute	155	
A New Non Linear Analysis Method and Its Application to Quartz Crystal Resonator Problems – J. H. Balbi and J. A. Duffaud, C.N.R.S. and R. J. Besson, E.N.S.C.M.B	162	
Analytical Calculation of Initial Stress Effects on Anisotropic Crystals: Application to Quartz Resonators	169	
- D. Janiaud, ONERA, L. Nissim, Quartz et Electronique and J.J. Gagnepain, C.N.R.S Static and Dynamic Frequency-Temperature Behavior of Singly and Doubly Rotated,	109	
Oven-Controlled Quartz Resonators - A. Ballato and J. R. Vig, USAERADCOM	180	
SAW Materials and Resonator Observations		
Progress in Closing the Lithium Niobate - ST Cut Quartz Piezoelectric Coupling Gap - R. M. O'Connell and P. H. Carr, Rome Air Development Center	189	
Experimental Measurement of the SAW Properties of Berlinite ^a) - D. G. Morency, W. Soluch, J.F. Vetelino, S. D. Mittleman, D. Harmon, S. Surek and J. C. Field, University of Maine	196	
Holographic Displacement Amplitude Measurements of Four Anharmonic at Modes - L. C. Barcus, University of Lowell	202	
Some Observations Using Scanning Electron Microscope For Studying The Ultrasonic Vibrations of Quartz Crystals		
- H. Bahadur*, A. Hepworth**, V.K. Lall** and R. Parshad*, *National Physical Laboratory (India); **India Institute of Technology	207	
Crystal Filters		
Some Recent Advances in Integrated Crystal Filters - R. C. Smythe, Piezo Technology Inc	220	
A Polylithic Crystal Filter Employing A Rhodes Transfer Function - P. A. Herzig and T. W. Swanson, E-Systems, ECI Division	233	
A Selective Linear Phase Crystal Filter - P. Siffert and J. Kerboull, CEPE	244	
Crystal Filter AM-PM Conversion Measurements - T. W. Swanson, E-Systems, ECI Division	250	
Resonator Design		
Rotated X-Cut Quartz Resonators for High Temperature Applications - E.P. EerNisse, Sandia Laboratories	255	
Energy Trapping of Coupled Modes in Rectangular At-Cut Resonators - A. E. Zumsteg, P. Suda and W. Zingg, SSIH Electronic SA	260	
A 4.19MHz Beveled Miniature Rectangular AT-Cut Quartz Resonator - S. Yamashita, N. Echigo, Y. Kawamura, A. Watanabe, K. Kubota, Daini Seikosha Co., Ltd	267	
+5 ^O X Micro Quartz Resonator by Lithographic Process - K. Oguchi, E. Momosaki, Suwa Seikosha Co., Ltd	277	
Resonator Processing		
Design and Implementation of an Etch System for Production Use - D. Ang, Tyco Crystal Products Inc	282	
Simplified Fixtures with Improved Thin Film Deposition Uniformity on Quartz Crystals - G. L. Dybwad, Bell Telephone Laboratories	286	
Polyimide Bonded Resonators - R. L. Filler*, J.M. Frank**, R.D. Peters**, and J.R. Vig*, *USAERADCOM, **GEND	290	

		Page
Frequency Tuning of Quartz Resonators by Plasma And - J.J.H. Reche, GTE Lenhurt Electric (Canada)	dization Ltd	299
Resonator Processing Continued		
Final X-Ray Control of the Orientation of Round or Industrial Purposes		
- J. F. Darces and H. Merigoux, Université de	Franche-Comté	304
Goniometric Measurements of the Angles of Cut of Do - J. Clastre, Universite de Bordeaux, C. Pegeo SECASI	oubly Rotated Quartz Plates ot, Quartz et Electronique and P.Y. Leroy,	310
Fully Automated Piezogoniometer (Automatic Quartz P	Plato Classifier)	
- Y. Kobayashi, Rigaku Corporation	Tate Classifier)	317
Basic Considerations on Metal Canned Enclosures for - D. Fuchs, Jenaer Flaswerk Schott & Gen	the Encapsulation of Quartz Crystal Units	321
Specification and Measurement		
Derivation of a Leak Specification for a Hermetic E	Envelope	
- J. H. Sherman, Jr., General Electric Company	/	
Crystals and NMOS: Frequency Controlled MPU's - J. J. Farrell, Motorola		
- J. J. Farrell, Motorola		334
The Measurement of Load Resonance Characteristics of Phase II-Network		Or Dec
- S. J. Hughes, R. W. Parfitt and J. S. Hardy,	, Royal Aircraft Establishment	337
Results of Temperature Slewing Quartz Crystals for - M. B. Bloch, M. P. Meirs and A. Strauss, Fre	equency Electronics, Inc	344
Automatic Microcircuit Bridge Measurements on Quar - G. Malinowski and E. Hafner, USAERADCOM	tz Crystal Units	354
Frequency Generation		
A General Purpose LSI Frequency Synthesizer System		
- M. J. Underhill, P.A. Jordan, M.A.G. Clark a		365
Laboratories		
HF Frequency Synthesizer Adaptive to Various Tuning - D. E. Phillips, Collins Telecommunications P	Time and Frequency Increment Requirements	373
Voltage-Controlled Oscillator with Time-Delay Feedb	and b	
-J.B.L. Rao and W. M. Water, Naval Research La		378
10 GHz Cavity Stabilized FET Oscillator - B. E. Rose, Hughes Aircraft Company		385
- b. c. nose, nagnes Arretare company		
Crystal Oscillators		
Dual Mode Operation of Temperature and Stress Compe - J. A. Kusters, M. C. Fischer and J. G. Leach	ensated Crystals	389
Temperature Compensation of Crystal Oscillator by M - M.Onoe, I. Yamagishi and H. Nariai, Universi	licroprocessor ty of Tokyo	398
Highly Precise Standard Signal Circuit for Timepiec - Y. Akahane, Suwa Seikosha Co., Ltd	e e e e e e e e e e e e e e e e e e e	403
Mathematical Analysis and Design of an Ultra Stable	Low Noise 100 MHz Crystal Oscillator	
with Differential Limiter and Its Possibilities in Frequency Standards - U. L. Rohde, University of Florida	Frequency Standards	409
Improvement in System Performance Using a Crystal O	scillator Compensated for Acceleration	
Sensitivity - J. M. Przyjemski, The Charles Stark Draper L	aboratory, Inc	426

	No.
A Technique for a Self Phase Noise Measuring System for Signal Sources - B. Parzen and J. P. Hou, Frequency Electronics, Inc	432
Atomic and Molecular Frequency Standards - New Concepts and Devices	
Saturated Absorption Optical Ramsey Fringes - J. C. Bergquist, R. L. Barger, and D. J. Glaze, NBS	439
Analysis of New Microwave and Optical Frequency Standards Based on Ions Storage - F. Strumia, Pisa University (Italy)	444
New Possibilities for Frequency Standards Using Laser Cooling and Detection of Stored Ions - F. L. Walls, D. J. Wineland, and R. E. Drullinger, NBS	453
A New Low Voltage, Maintenance-Free, Cesium Beam Tube for a Frequency Standard - H. Jumonji and K. Tanaka, Yokosuka Electrical Communication Laboratory and J. Toyama, H. Takaoka, K. Kariya and J. Kawada, Fujitsu Limited	460
Parameters Affecting the Stability of an Optically Pumped Cesium Frequency Standard - G. Rovera and S. Leschiutta, Istituto Elettrotecnico Nazionale; G. Busca, Universite Laval and F. Strumia, Pisa University	466
Small, Very Small, and Extremely Small Hydrogen Masers - Harry E. Peters, Sigma Tau Standards Corporation	469
Performance Evaluation of the SAO VLG-11 Atomic Hydrogen Masers - M. W. Levine, R. F. Vessot and E. M. Mattison, Harvard College Observatory and Smithsonian Astrophysical Observatory	477
NASA NR Hydrogen Maser - L. J. Rueger, A. Bates, L. Stillman, J. Norton and C.M. Blackburn, The John Hopkins University, and V. A. Reinhardt NASA	486
A Passive Hydrogen Maser Frequency Standard - F. L. Walls and D. A. Howe, NBS	492
An Operating Development Model Spacecraft Hydrogen Maser - E. S. Sabisky and H. A. Weakliem, RCA David Sarnoff Research Center	499
Effect of Line Inhomogeneity on the Frequency of Passive Rb ⁸⁷ Frequency Standards. - A. Risley, NBA and G. Busca, Laval University	506
The Precision Frequency Standard as a System	
Conversion Between Time and Frequency Domain of Intersection Points of Slopes of Various Noise Processes	514
- R. Burgoon and M. C. Fischer, Hewlett-Packard Company	514
Transfer of Frequency Stability From an Atomic Frequency Reference to a Quartz Crystal Oscillator	500
- J. Vanier, M. Tetu and L.G. Bernier, Universite Laval	520
A Systems Approach to High Performance Oscillators - S. R. Stein, C. M. Manney, Jr., F. L. Walls, J. E. Gray, NBS and R. J. Beeson, ENSCMB	527
Analysis of H-Maser Autotuning Systems - C. Audoin, P. Lesage, J. Viennet and R. Barillet, CNRS	531
A & M Devices - Application and Evaluation	
Estimation of the Spectrum of Fractional Frequency Deviates - D. B. Percival, U.S. Naval Observatory	542
Theoretical Performance of Frequency Estimators Using Phase-Locked Loops - T. A. Schonhoff, GTE Sylvania, Inc	549
Applications of Atomic Frequency Standards to Satcom Spread Spectrum Systems - S.A. Nichols, D.G. Woodring, Naval Research Laboratory	555
NTS-2 Cesium Frequency Stability Results - T. McÇaskill, J. White, S. Stebbins, J. Buisson, Naval Research Laboratory	560
INDEX OF AMTHORS.	567
SPECIFICATIONS AND STANDARDS GERMANE TO FREQUENCY CONTROL	

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Summary

Samples of quartz obtained over several years from 12 suppliers have been examined. Hydrogen is found to be the major impurity. Infra-red measurements show that there are linear relations between the absorption due to hydrogen at 3585, 3500, 3410, 3300 and 3200 cm⁻¹. A consideration of the intrinsic and practical problems of using each of these absorptions suggests that it is advantageous to use the absorption at 3410 cm⁻¹ and a simple reciprocal relation between Q and the appropriately corrected extinction coefficient is suggested.

Measurements of infra-red Q at various positions in a crystal show that significant changes only occur in general due to changing the position of the measured sample in the Z direction. These changes become large as the average Q falls. Similarly comparing the mean Q's of crystals from one batch shows that deviations from the batch mean increase as the batch mean falls. It is also shown that there is an inverse correlation between dislocation density and Q.

Introduction

The electromechanical Q of a quartz crystal is a useful guide to its suitability for various applications. Because high Q material must be grown slowly 1-4, it is expensive and should not be used unnecessarily. Direct measurements of Q are difficult to make. Thus a simple indirect method of measurement is needed. Dodd and Fraser 5 showed that there is a good correlation between electromechanical Q and infra-red absorption and this method is now used by most workers in the field. Sawyer 6 showed that the relation took the form

$$Q^{-1} = Q_0^{-1} + A\alpha + B\alpha^2$$
 (1)

where α is the extinction coefficient. Strictly, α is defined so that the fractional intensity of light transmitted through a parallel sided sample of thickness t is

$$T = \frac{(1 - R)^2 \cdot 10^{-\alpha t}}{1 - R^2 \cdot 10^{-2\alpha t}}$$
 (2)

where R is the reflection coefficient of the sample surfaces and the denominator allows for the

effect of multiple internal reflections. For quartz in the near infra-red, R is about 4% so that the term R^2 $10^{-2}\alpha t$ has a maximum value of less than 2 x 10^{-3} and can be neglected. However a reliable estimate of α still required measurements to be made on samples with different thicknesses. This was done by Lias et al 2 but other workers 6 -10 compare measurements at two wave numbers, one of which is chosen to have negligible absorption but essentially the same reflection coefficient as the frequency of interest. Then

$$\alpha = \left[\log_{10} \left(T_{ref} / T_{v} \right) \right] / t \quad (3)$$

where $T_{\rm ref}$ is the transmitted intensity at the reference wave number (usually 3800 or 3900 cm⁻¹) and $T_{\rm U}$ is the transmission at the wavenumber of interest. Table 1 summarizes the data in the literature in terms of coefficients in equation (1). Lias et al 3 give data which relates α and hydroxyl content. At 3500 cm⁻¹ they find that α = 1 cm⁻¹ corresponds to 4800 ppm H measured relative to silicon. Sawyer 6 suggests a figure of 6000 ppm (cm⁻¹)-1.

This paper compares results obtained at the various wavenumbers sensitive to the presence of OH and shows that there are significant effects due to finite absorption independent of the hydroxyl content and that apparatus parameters (resolving power and polarization) can appreciably alter the results obtained. From the results obtained it is also shown that the variations of Q within a crystal and between crystals in a batch both increase as Q falls and that there seems to be an inverse correlation between Q and dislocation density.

Experimental

Samples were cut from crystals with Y-bar or Y-plate seeds obtained over a six year period from 12 suppliers (3 in the USA, 4 in Europe, 2 in Japan and one each in Russia, China and South America). From each supplier we obtained as many grades of material as possible. Thus the samples should be a representative selection of materials grown from various raw materials with a reasonable range of growth parameters. Table 2 gives the impurity contents found and shows that hydrogen is always the major impurity on an atomic basis. The only other significant trends observed were that high Q crystals tended to have less of all the impurities than low Q crystals (the upper quartile

data are typical of crystals with a Q of about 1×10^6 and the lower quartile figures are typical of samples with a Q of 2×10^6). Note also the effect of mineralizer on carbon content.

The samples for infra-red measurements were usually plates with faces including the X and Z axes and the radiation was propagated parallel to Y. The samples were polished usually finishing with Syton but for some samples we used cerirouge. If these samples were repolished on Syton, no significant differences were seen optically but double crystal reflection topographs showed that the cerirouge finish left some surface strains.

The measurements were made at room temperature (20 ± 5°C) generally using a Perkin-Elmer 337 double beam spectrometer. The beam size was stopped down to 5mm diameter. Because of the use of a reflecting optical system the radiation was polarized so that about 70% of the electric vector lay in a horizontal plane. We measured the crystals with the optic axis horizontal and vertical and deduced values of respectively a11 and α_1 as discussed later. The symbol a is used to imply the mean of these measurements. Similarly T implies the mean of the two transmitted Comparing our results with those intensities. obtained on the same samples with 3 other spectrometers showed that in general the T values agreed to within ± 0.5% and results were reproducible to Thus we believe that our measureabout 0.2%. ments of the product at (equation 3) are accurate to \pm 0.005, i.e. for a 10mm thick sample we can measure α to \pm 0.005 cm⁻¹. The only exception to this was the measurement of α_{3585} . For this parameter we found that the resolving power of the For this instrument was important. Other spectrometers with resolving powers of about 4 cm⁻¹ like ours gave the same result but instruments with better resolving power (< 1.5 $\,\mathrm{cm}^{-1}$) gave values which were higher by 15% on average. Thus for this line instrument resolving power is important. Other workers find the same effect. Thus due to a change in resolving power the calibration curves given in references 9 and 10 differ by a factor 2.

We measured plates between 1 and 20 mm thick but discarded results on plates less than 7 mm thick except for measurements of absolute absorption. We also discarded measurements on crystals which reflection topographs showed to be highly strained. These crystals could have values of $\alpha_{11}:\alpha_{1}$ which were radically different from the average e.g. 2.

Attention was concentrated on the Z growth zone and only these results are discussed in the next section. Values of α in the +X zone were usually larger than in the Z zone. This would be expected from the greater segregation coefficients (see reference 11 for a discussion of this).

Results and Discussion

Figure 1 shows the general features of the transmission spectrum of a typical sample. The two curves are for the same area but the upper

curve is T_1 and the lower curve is T_{11} . Kats ¹² observed a similar sensitivity to polarization. His results taken at a temperature of 78K with 100% polarization show larger ratios than our data for about 300K with 70% polarization, see Table 3, which indicates that polarization effects can be significant.

Most workers use absorption at 3500 ${\rm cm}^{-1}$ as a ure of the quality of the crystals. Kats 12 measure of the quality of the crystals. has shown that much of the absorption in the near infra-red is due to hydrogen. Thus the lines at 3517, 3510 and 3485 are associated with hydrogen alone and the lines at 3513, 3510 and 3500 are associated with hydrogen and Na, Li and Ag respectively. Figure 1 shows that the absorption changes rapidly with wavenumber in this region. Typically a 1 cm $^{-1}$ change in wave number changes α by 1%. Few spectrometers are reproducibly accurate to more than a few cm-1 so that errors of a few per cent can occur from using this absorption. A self locating line is therefore desirable but as was shown in the last section the line at 3585 cm-1 is so narrow that the result obtained depends to a large extent on the instrument resolving power. Kats 12 shows that this line is associated with H alone or H + K. The absorptions at 3410, 3300 and $3200~{\rm cm}^{-1}$ are similarly associated with hydrogen with possible components due to hydrogen plus Na, Ag, Li and Cu. Kats 12 shows that there are lattice absorptions at 3396, 3300, 3220 and 3204 $\rm cm^{-1}$ and the half widths of these absorptions are typically 20 cm-1 so that a combined H and lattice effect is likely to be seen. However the lines at 3410, 3300 and 3200 cm⁻¹ are easily located and the line at 3410 is very broad and therefore easy to locate and measure with any spectrometer.

Figure 2 gives data comparing α_{3410} with α_{3500} which from the published data 2, 13 seems to be linearly proportional to hydroxyl content. (The value of α_{3585} is similarly linearly related to hydroxyl content 13). The average data spread on Figure 2 is $^{\pm}$.7% about the line

$$\alpha_{3410} = 0.050 + 1.25\alpha_{3500}$$
 (4).

This data spread is expected on the basis of experimental errors. Similarly we find that with spreads of $\overset{+}{\sim}$ 8% the other relative extinction coefficients (equation 3) can be given by

$$\alpha_{3300} = 0.125 + 0.80\alpha_{3500}$$
 (5)

and

$$\alpha_{3200} = 0.110 + 0.60\alpha_{3500}$$
 (6).

Our measurements of $\alpha3585:\alpha3500$ show that the average value is 1.03 ± 0.08 . It is possible that the ratio is slightly dependent on α . We find a ratio of 0.97 ± 0.05 for $\alpha<0.1$ cm⁻¹ and 1.07 ± 0.05 for $\alpha>0.1$ cm⁻¹. These differences are probably due to the resolving power effect already discussed. The uncertainties quoted in all these instances are spreads of the data points. Uncertainties in the mean values are much less.

In general our data show that for unstrained

samples there is little variation in the transmission of any sample in the range 4000 to 3760 cm⁻¹. (Badly strained samples show reproducible variations in this range.) However we did observe that the values of T varied with thickness from about 83 to 94%. Figure 3 plots the average values as a function of sample thickness. The slope of the line on this figure suggests an intrinsic extinction coefficient of 0.025 ± 0.002 cm⁻¹ in this range. Kats 12 suggests that there may be lattice absorptions. If this is the case then the relative extinction coefficients (equation 3) will be smaller than the absolute ones (equation 2) and to convert from relative to absolute we must add 0.025 cm⁻¹. If this is done, equations (4) to (6) become

$$\alpha_{3410} = 0.044 + 1.25\alpha_{3500}$$
 (7)

$$\alpha_{3300} = 0.130 + 0.80\alpha_{3500}$$
 (8)

and
$$\alpha_{3200} = 0.120 + 0.60\alpha_{3500}$$
 (9)

Thus the intrinsic lattice absorptions at these frequencies correspond to absolute extinction coefficients of 0.044, 0.120 and 0.110 cm $^{-1}$. To obtain the hydroxyl related extinction coefficient from a relative one we must allow both for these absorptions and the intrinsic absorption at the reference frequency. Thus we add 0.025 cm $^{-1}$ at 3500 and 3585 cm $^{-1}$ and subtract 0.019, 0.105 and 0.095 cm $^{-1}$ at 3410, 3300 and 3200 cm $^{-1}$ respectively. Values treated in this way are denoted by α^{\star} .

Figure 4 shows a plot of Q against α^{\bigstar} using the published data. It can be seen that for 3500 cm^{-1} the data are well represented by

$$Q = C \times 10^5 / \alpha_{3500}^*$$
 (10)

where C = 1.35. The spread is that expected from experimental errors. The Toyo data for 3585 cm $^{-1}$ seem to be well represented by the same equation but from our measurements we expect C3585 = 1.39 or for a spectrometer with a resolving power of better than 1.5 cm $^{-1}$, C3585 should be 1.60. Similarly at the other wavenumbers we can derive values of C from equations (7) to (9) which are C3410 = 1.69, C3300 = 1.08 and C3200 = 0.81. In practice only the absorption at 3410 cm $^{-1}$ offers any appreciable advantage and we recommend the use of this line and the relation

=
$$1.69 \times 10^5 / \alpha_{3410}^*$$
 (11)

There seems little doubt that a relation like (10) or (11) can be used with at least the same degree of confidence as any of the relations given in Table 1.

Now that we have a measurement technique, there is still a sampling problem: one measurement of Q does not characterize a crystal and measurements on one crystal do not characterize a batch grown in the same autoclave at the same time. Looking first at the variations in one crystal, we find that moving the beam in the X direction does not change α significantly unless there is a sub-

boundary (Figure 5) and such regions give large polarization effects: $\alpha_{11}:\alpha_1$ ratios of 1.5 or even 2. Similarly, if we measure another slice from the same crystal and make our measurement at the same distance from the seed, the changes are barely significant 15% for a Q of 1.0 \times 10⁶, 10% for a Q of 1.5 \times 10⁶ and perhaps 5% for a Q of 2.5 \times 10⁶. However when the beam is moved parallel to the Z axis large changes occur. Figure 6 shows the average change $\Delta\alpha^{\pi}$ obtained by moving a 5mm diameter beam in the Z direction by 5mm. The value of α decreases by an amount $\overline{\Delta\alpha^*}$ on moving outwards. The figure gives the mean value of $\overline{\Delta\alpha}^{*}$ as a function of the average of the two measured values of a*. For most purposes the values of $\overline{\Delta \alpha^*}$ and $\overline{\alpha^*}$ probably characterize the crystal adequately. If we now examine the variations within a batch of Q deduced from at we find the relation shown on Figure 7. The values obtained for batches with the same mean Q are surprisingly The standard error of the standard constant. deviation is only about 20%. Thus we can use Figure 7 to deduce confidence limits based on measurements of a relatively small sample of crystals from one batch.

Because we had topographs of samples from crystals with known Q we could correlate dislocation densities with Q as shown on Figure 8. On this figure, open circles are median values and the filled circles and triangles represent respectively the maximum and minimum values found in batches of 8 to 12 samples. Thus it appears that a Q specification also fixes the likely range of dislocation densities. A relation between dislocation density and Q or α is reasonable on the model proposed by Griggs 14 who suggests that dislocations are surrounded by a cloud of hydroxyl ions and Ayensu and Ashbee 15 have proposed that dislocation movement requires OH ions. (Dislocation generation requires dislocation movement.)

Conclusions

This paper has shown that infra-red measurements can be used to characterize quartz. In order to obtain reasonable accuracy a relatively thick sample must be examined: for measurement of high Q's a sample 10mm or more thick must be used. Account must be taken of polarization effects and intrinsic absorptions but if these are treated correctly a simple reciprocal relation gives Q. It is specifically recommended that when comparable results are required from different instruments the absorption at 3410 cm⁻¹ should be used. Absorption at this wave number has the following advantages:

- (a) It shows the maximum sensitivity to hydroxyl concentration.
- (b) The line is easily located.
- (c) The line is broad so that no problems are experienced with resolution or instrument calibration.
- (d) The correction needed to convert relative extinction to absolute extinction due to hydroxyl is the smallest of any line considered.

(e) The polarization effect is small.

It is also necessary to measure at more than one location relative to the seed. If all these factors are taken into account then a batch can be characterized by measurements on a relatively few specimens. The polarization effect can be used to detect strained crystals and it appears that a measurement of Q fixes the range of dislocation densities likely to be found.

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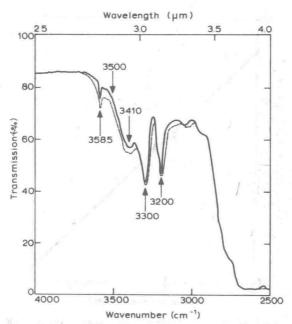


Figure 1. The transmission spectrum of a 20mm thick sample. The full line is obtained when the major part of the electric vector is parallel to Z. The broken line is the result obtained with the sample rotated 90° about Y.

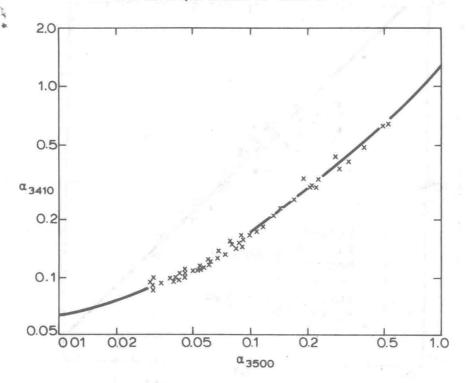


Figure 2. The comparison of α_{3410} with α_{3500}

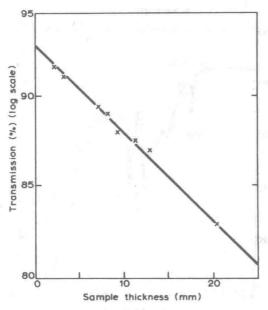


Figure 3. Average transmission in the range 3800 to 3900 ${\rm cm}^{-1}$ as a function of sample thickness.

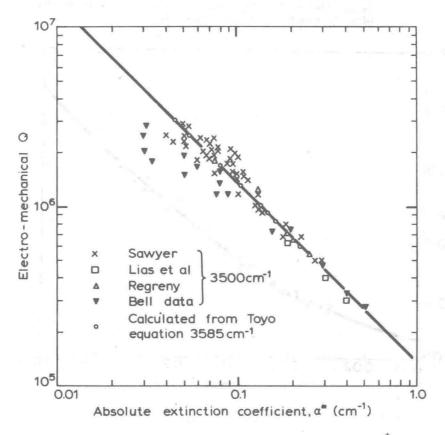


Figure 4. Published data on Q plotted as a function of α^* .

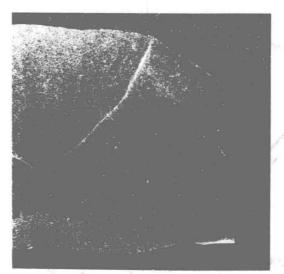


Figure 5. A double reflection X-ray topograph showing a "sub-boundary" in the Z zone.

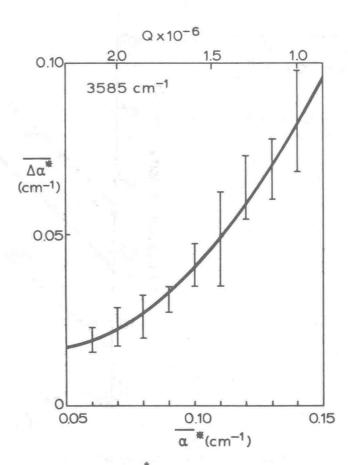


Figure 6. The change in α^* found on moving 5mm in the Z direction as a function of the mean value of α^* .

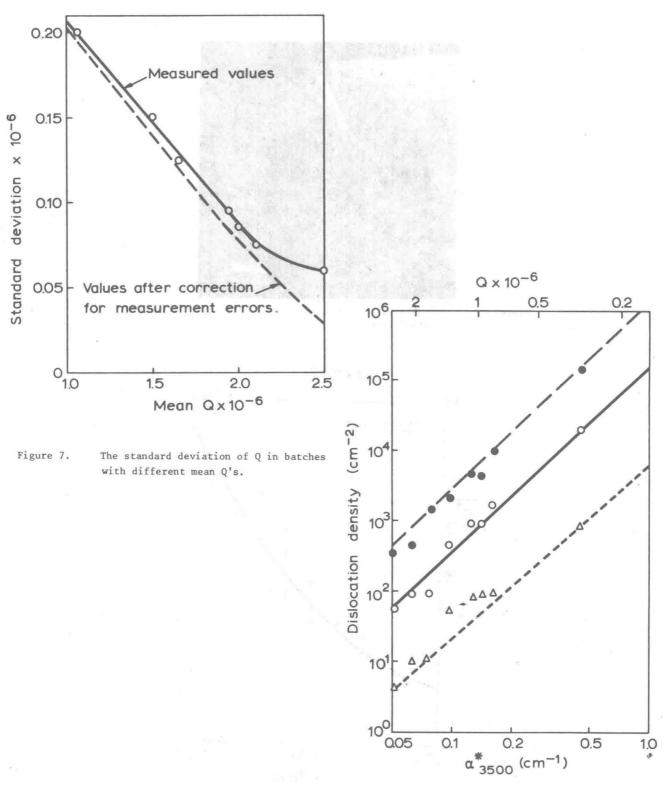


Figure 8. Dislocation density as a function of α^* . The full line is median values. The broken lines represent maximum and minimum observed values.